



00862.022199.

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Keiji EMOTO

Application No.: 09/833,766

Filed: April 13, 2001

For: PIPE STRUCTURE, ALIGNMENT APPARATUS,  
ELECTRON BEAM LITHOGRAPHY APPARATUS,  
EXPOSURE APPARATUS, EXPOSURE APPARATUS  
MAINTENANCE METHOD, SEMICONDUCTOR DEVICE  
MANUFACTURING METHOD, AND SEMICONDUCTOR  
MANUFACTURING FACTORY

Examiner: P. L. Rodriguez

Group Art Unit: 2125

Confirmation No.: 4154

**RECEIVED**

**SEP 22 2004**

**Technology Center 2100**

September 20, 2004

**Mail Stop Amendment**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

Transmitted herewith is an Amendment in the above-identified application.

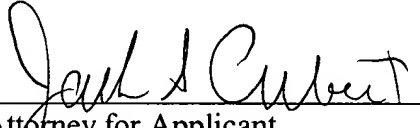
☒ No additional fee is required.

The fee has been calculated as shown below:

CLAIMS AS AMENDED						
	CLAIMS REMAINING AFTER AMENDMENT		HIGHEST NO. PREVIOUSLY PAID FOR	PRESENT EXTRA	RATE	ADDITIONAL FEE
TOTAL CLAIMS	10	MINUS	27	= 0	x \$9 \$18	\$0.00
INDEP. CLAIMS	2	MINUS	11	= 0	x \$43 \$86	\$0.00
Fee for Multiple Dependent claims \$145/\$290						—
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT						\$0.00

- ☐ °Verified Statement claiming small entity status is enclosed, if not filed previously.
- ☐ A check in the amount of \$\_\_\_\_\_ is enclosed including the additional claims fee.
- ☐ Charge \$\_\_\_\_ to Deposit Account No. 06-1205. A duplicate of this sheet is enclosed.
- ☒ Any prior general authorization to charge an issue fee under 37 CFR 1.18 to Deposit Account No. 06-1205 is hereby revoked. The Commissioner is hereby authorized to charge any additional fees under 37 CFR 1.16 and 1.17 which may be required during the entire pendency of this application, or to credit any overpayment, to Deposit Account No. 06-1205. A duplicate of this paper is enclosed.
- ☐ A check in the amount of \$\_\_\_\_\_ to cover the fee for a two month extension is enclosed.
- ☐ A check in the amount of \$\_\_\_\_\_ to cover the Information Disclosure Statement fee is enclosed.
- ☒ Applicant's attorney, Steven E. Warner, may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should be directed to our address given below.

Respectfully submitted,

  
\_\_\_\_\_  
Attorney for Applicant  
Jack S. Cubert  
Registration No. 24,245

FITZPATRICK, CELLA, HARPER & SCINTO  
30 Rockefeller Plaza  
New York, New York 10112-3800  
Facsimile: (212) 218-2200  
SEW/JSC/dc

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PATENT APPLICATION

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In re Application of:	)	
Keiji EMOTO	)	: Examiner: P. L. Rodriguez
Application No.: 09/833,766	)	: Group Art Unit: 2125
Filed: April 13, 2001	)	: Confirmation No.: 4154
	)	: September 21, 2004
For: PIPE STRUCTURE, ALIGNMENT APPARATUS,	)	
ELECTRON BEAM LITHOGRAPHY	)	
APPARATUS, EXPOSURE APPARATUS,	)	
EXPOSURE APPARATUS MAINTENANCE	)	
METHOD, SEMICONDUCTOR DEVICE	)	
MANUFACTURING METHOD, AND SEMI-	)	
CONDUCTOR MANUFACTURING FACTORY	)	

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**SEP 22 2004**

**Technology Center 2100**

**Mail Stop Amendment**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

AMENDMENT

Sir:

In response to the Office Action dated June 21, 2004, please amend the above identified application as follows: